

# A Method of Image-Based Aberration Metrology for EUVL Tools

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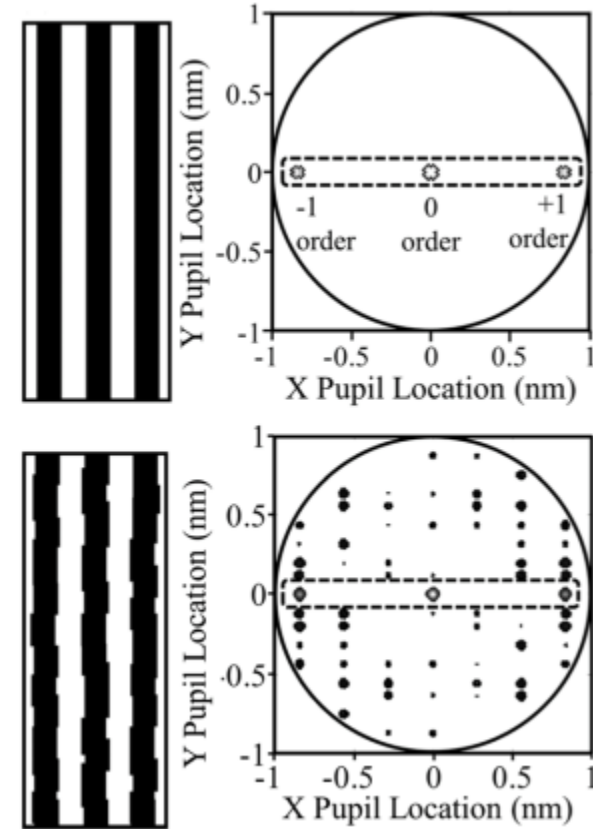
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# Introduction

- Pupil plane characterization continues to play a critical role in image process optimization moving into EUVL
- Additional importance in understanding the influence and variations of aberrations during system use
- At RIT we have developed a method to measure optical aberrations of EUVL systems from images formed by that system



(Baylav et al., 2013)

# Introduction

- Past studies, and traditional aberration theory in general, have focused on evaluation of pupil phase variation
- Other system variations have been assumed to be small, but are potentially more important in EUV imaging.
- We examine the flexibility of an image-based method using two experimental case studies:
  - 1) Pupil phase variation of an ASML NXE:3100 exposure system using SEM image analysis through inverse solutions
  - 2) Amplitude *and* phase pupil variation in the SEMATECH High-NA Actinic Reticle review Project (SHARP)—an EUV mask microscope at Lawrence Berkeley National Laboratory



# Outline

- Modeling pupil variation
- Image-based method for pupil variation extraction
- Extraction of pupil amplitude variation
- Image-based metrology experiments
- Concluding remarks



# Modeling Pupil Variation

The transfer of light through an optical system in the frequency domain can be given by:

$$\widetilde{E}_i(u, v) = \widetilde{E}_o(u, v) \cdot P(u, v)$$



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We define the amplitude in terms of a slight perturbing function:

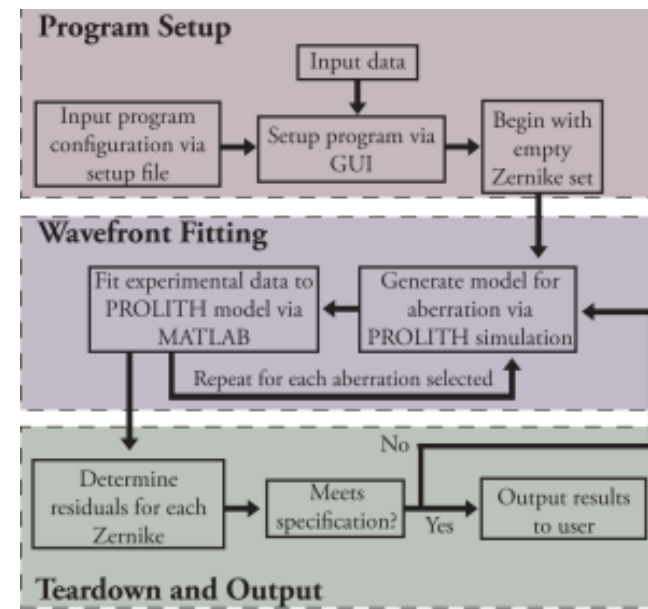
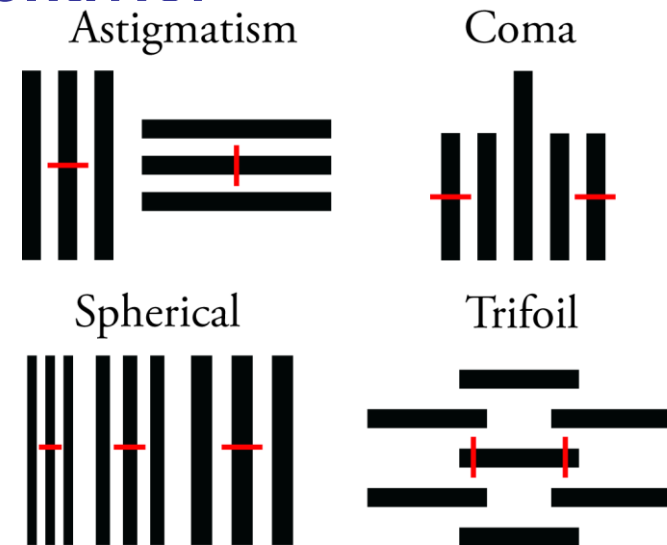
$$\alpha(\rho, \theta) = \begin{cases} 1 + A(\rho, \theta) & : \rho \leq 1 \\ 0 & : \rho > 1 \end{cases}$$



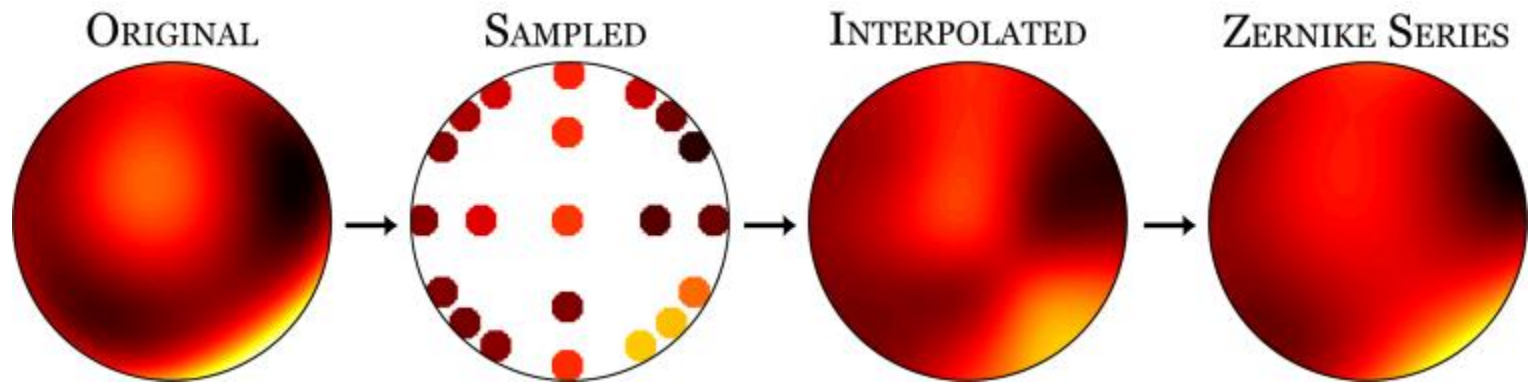
# Image-Based Method

Automated, iterative, model-based solutions to particular image behavior

- Aberrations measured via targets sensitive to specific aberrations
- Input data as CD or aerial image
- Provides in-situ aberration monitoring
- All targets need to be optimized for each tool/illumination
- Targets are generally available on existing reticles
- Has been demonstrated in the past for pupil phase extraction



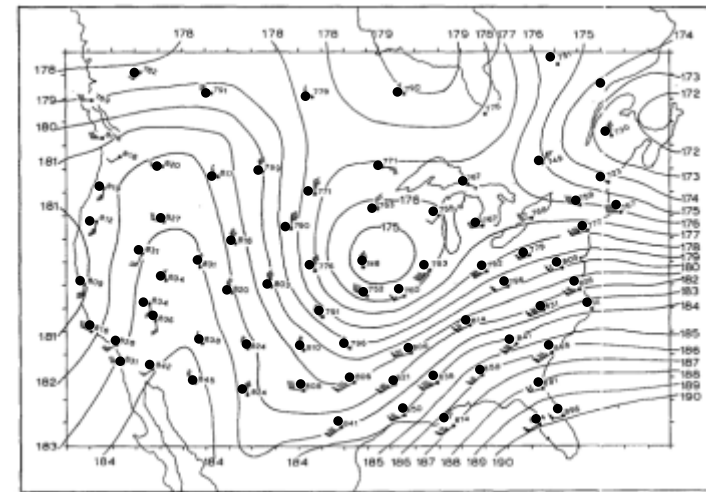
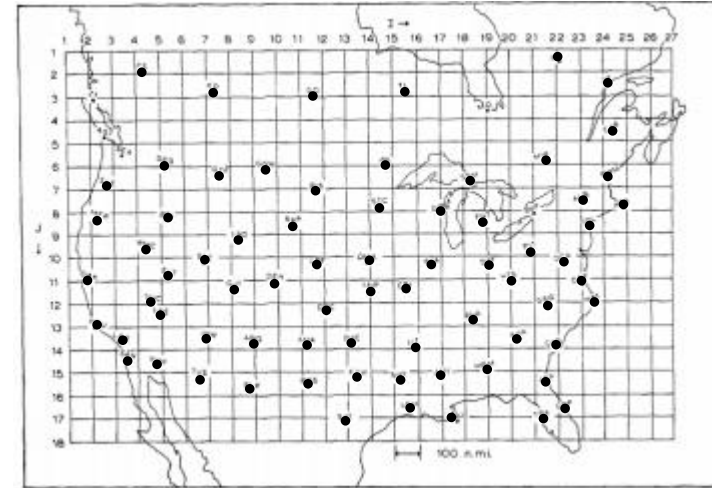
# Extraction of Pupil Amplitude Variation



- A partially coherent source samples the pupil function *and* averages across the source
- Aerial image simulations iteratively fit to determine source-average sample value
- Barnes objective analysis is used to interpolate across the pupil between samples

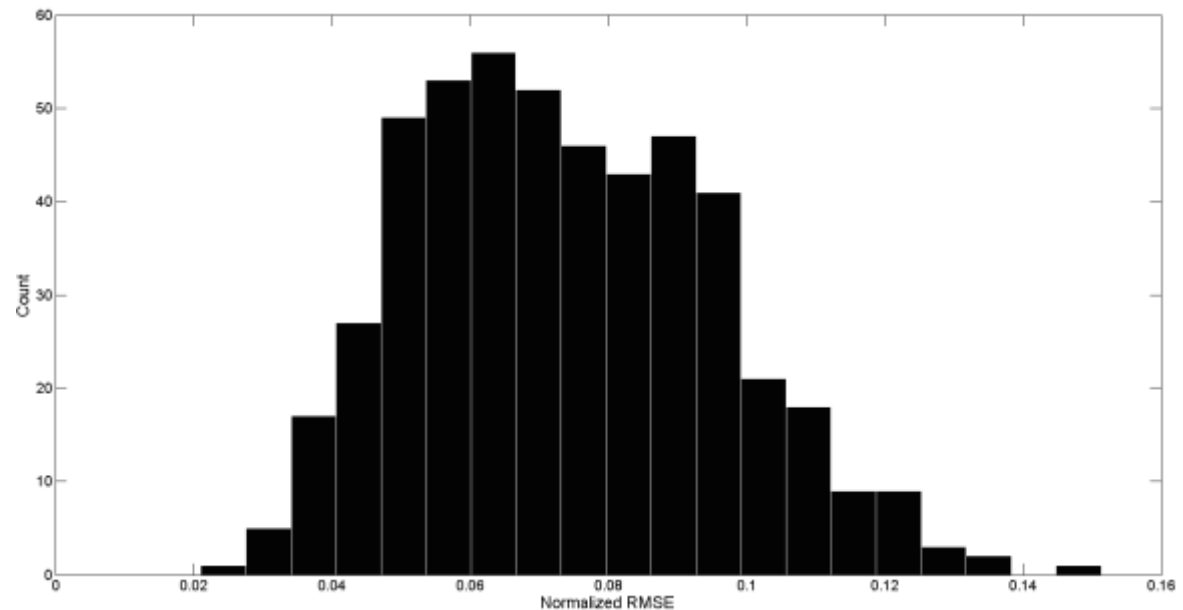
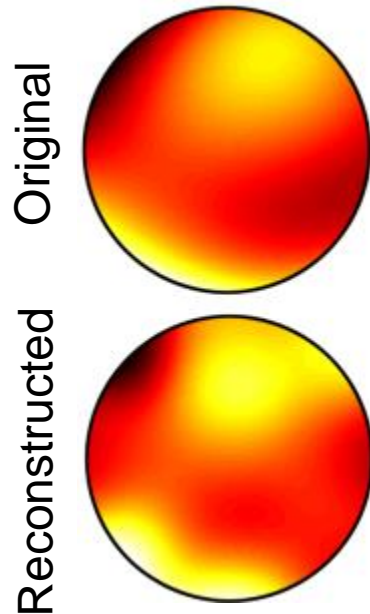
# Barnes Objective Analysis

- Commonly used in meteorological modeling
- Uses an initial guess for each grid point, then iteratively corrects it based on error computed from known values
- Weight of each error is inversely proportional to its distance from other points
- Highly accurate even when the samples are disordered and/or unevenly spaced



(Barnes, 1964)

# Extraction of Pupil Amplitude Variation

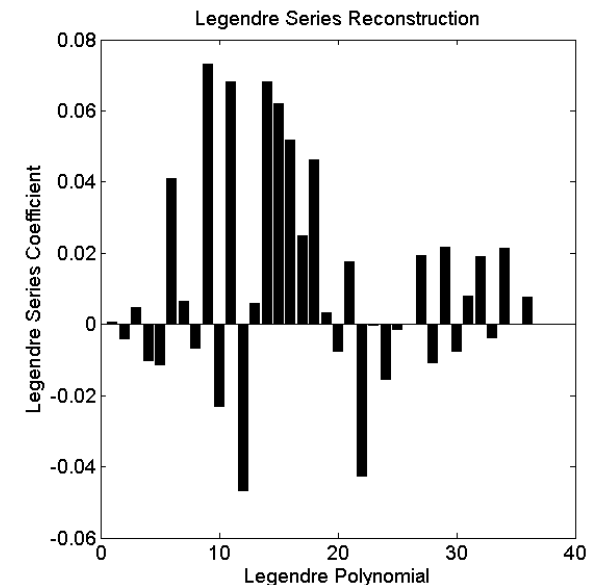
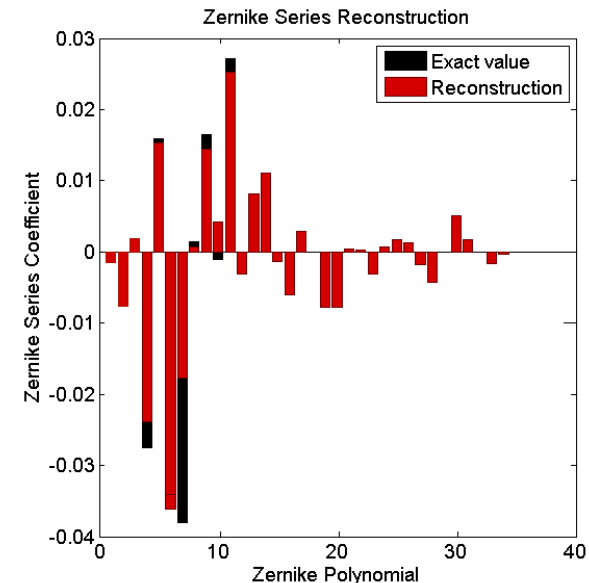


- 500 random amplitude functions comprised of third-order Zernike amplitude polynomials ( $Z_A5$ - $Z_A11$ ) sampled in  $\rho=0.5$  and  $\rho=0.9$  pupil zones with  $0.1\sigma$  source
- Residuals are  $\chi^2$  distributed with a mean around 6%

**Can reproduce the original function with little error from a small number of samples**

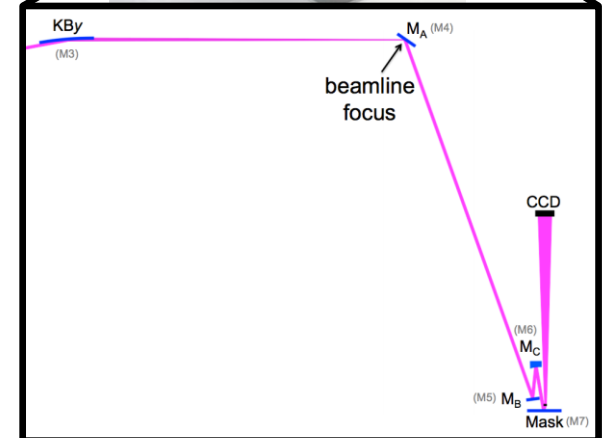
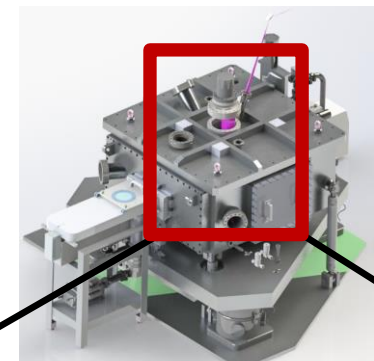
# Extraction of Pupil Amplitude Variation

- The original functions were made of Z5-Z11, but higher order terms appear in the reconstruction
- Blurring can be reduced by increasing the source coherence and the number of samples
- Function can still be represented with low error in less than 36 terms (~6% NRMSE)
- Expansion in the first 36 combinations of Cartesian Legendre polynomials would require more terms



# Image-Based Metrology Experiments

- ASML NXE:3100 Scanner
  - Full field catoptric lens
  - Fixed set of illuminators at 0.25NA
  - CD from SEM micrograph of resist patterns
- SEMATECH Actinic Reticle Review Project (SHARP)
  - Zone plate lens (0.25-0.625 4xNA)
  - Free form sources available by using MEMs mirror
  - Aerial image captured as CCD images



# Dominant Sources of Aberration: NXE3100 vs. SHARP

## NXE:3100

- Mask defectivity
- Multilayer mirror defectivity
- Each multilayer mirror reflection
- Thermal shifting

## SHARP

- Mask defectivity
- Multilayer mirror defectivity
- Zone plate lens
- Beam set-up/system alignment
- Thermal shifting



# NXE:3100 Target Selection

## Inputs

- Annulus 0.5/0.8 at 0.25 NA
- +75 nm focus offset

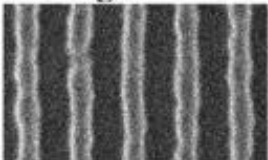
## Constraints

- NILS threshold of 2.0
- Aberration tolerance of mean ADT values

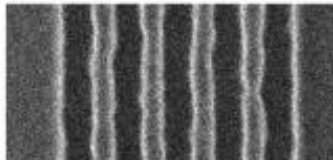
## Optimized targets

- 32 nm line/space array (astigmatism)
- 30 nm 5-bar (coma)
- 26 nm line through pitch (spherical)
- 35 nm t-bar (trefoil)

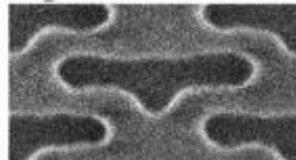
Astigmatism



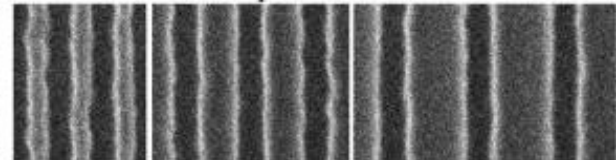
Coma



Trefoil



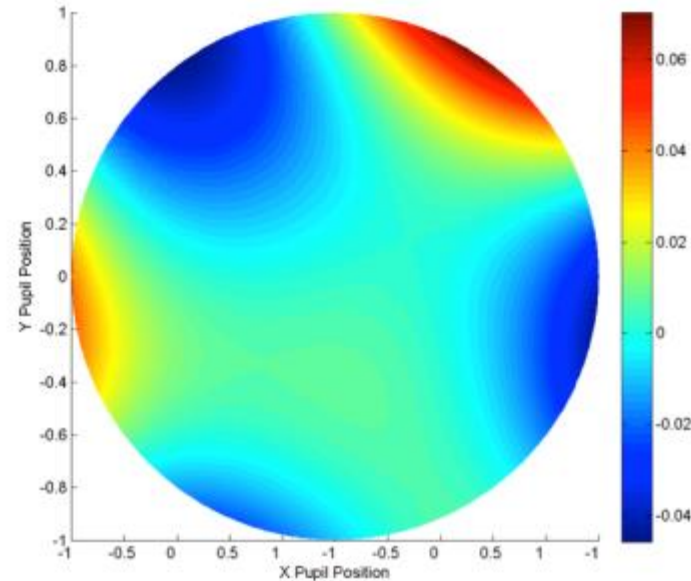
Spherical





# NXE:3100 Wavefront Extraction

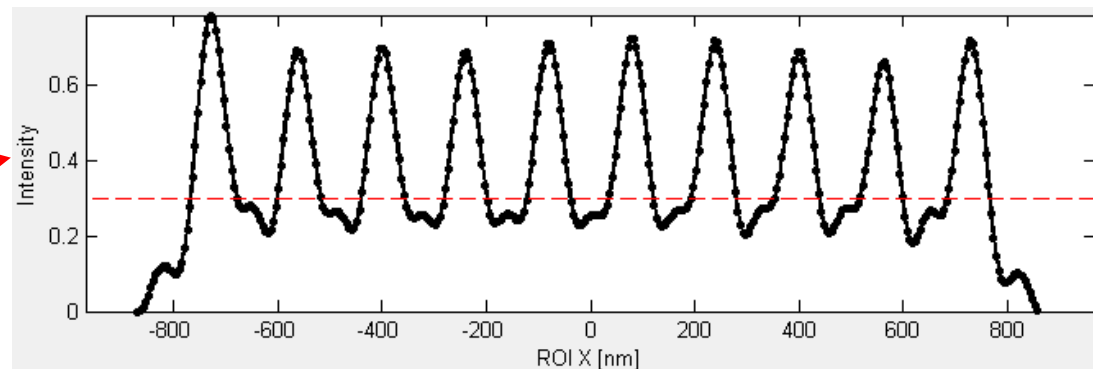
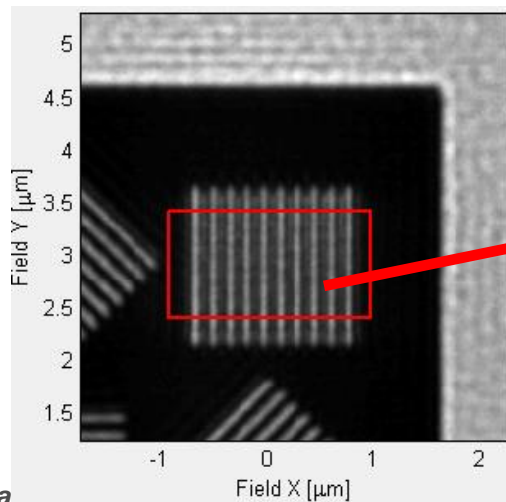
- Extracted NXE:3100 pupil phase variation
- CDs measured via custom offline metrology code
- 10 iterations were necessary to converge on a solution (~20 minute runtime)
- RMS of  $13.4m\lambda$  or 0.181 nm
- $\Delta$ CD MSE is the error in the analytical  $\Delta$ CD model



Aberration Name	Extracted Value [ $m\lambda$ ]	$\Delta$ CD Mean Square Error [ $nm^2$ ]
Astigmatism 90°	-0.82	0.136
Astigmatism 45°	+26.58	0.184
Coma X	-2.92	0.038
Coma Y	+12.00	0.043
Spherical	+0.15	N/A
Trefoil X	-36.09	1.032
Trefoil Y	+1.27	0.590

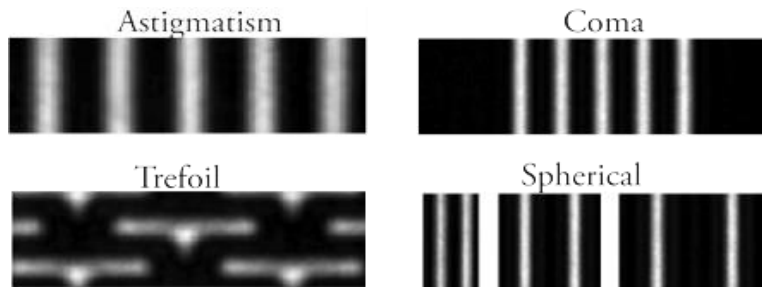
# SHARP Target Selection

- Very low partial coherence available ( $\sigma=0.1$  used)
- Records gray levels, so modulation is less important
- Accomplished by calculating the size/orientation required to sample the desired pupil locations ( $\rho=0.5$  and  $\rho=0.9$  pupil zones)
- Images were analyzed in custom image processing code



# SHARP Target Selection

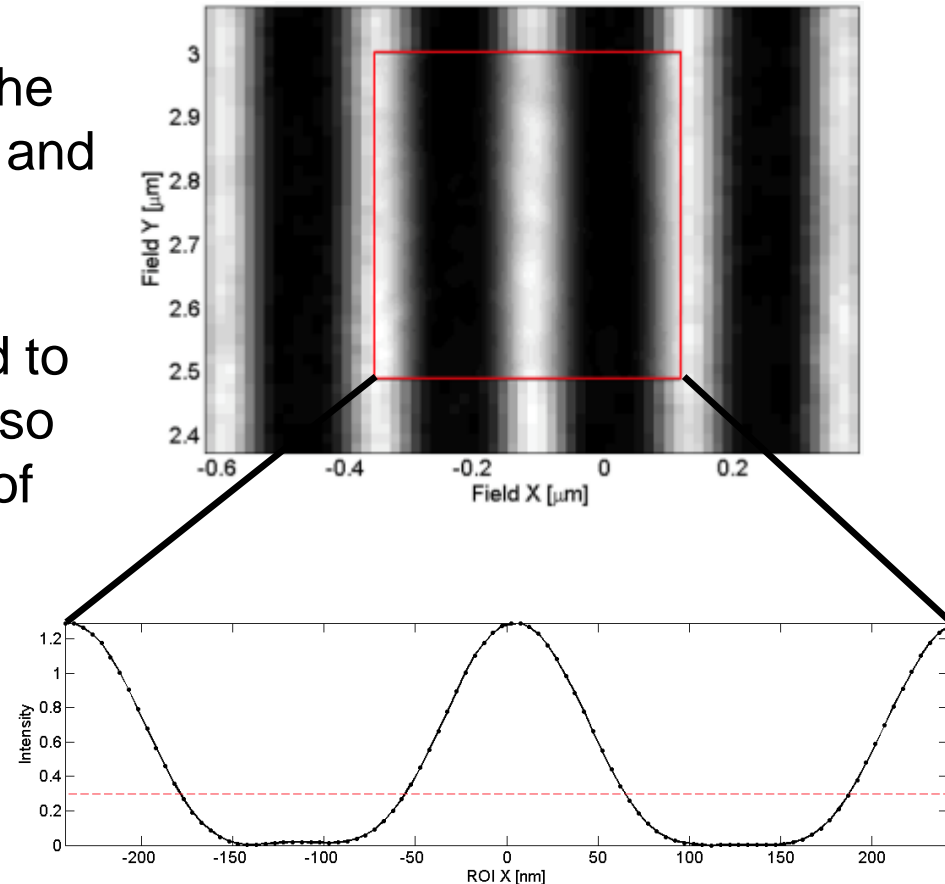
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Aberration Name	Structure Type	Target CD [nm]
Astigmatism 90°	Vertical/Horizontal Line/Space	30
Astigmatism 45°	45°/135° Line/Space	30
Coma X	Vertical 5-bar	50
Coma Y	Horizontal 5-bar	50
Spherical	Line through pitch	30
Trefoil X	Horizontal T-Bar	35
Trefoil Y	Vertical T-Bar	35

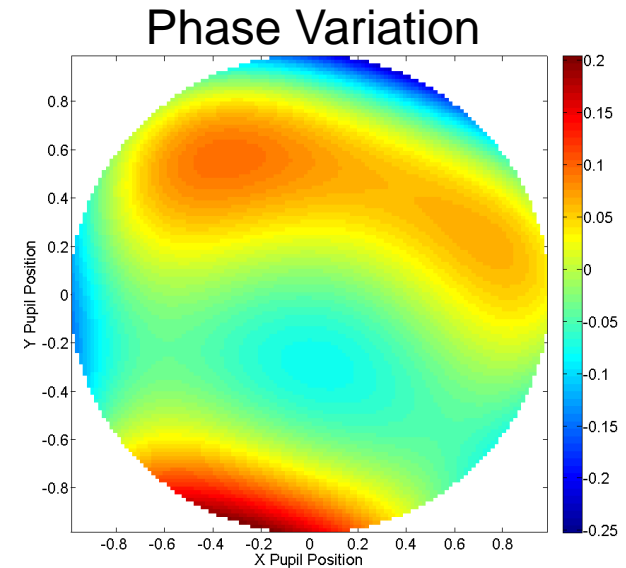
# SHARP Image Processing

1. Dark current noise from the CCD was subtracted from the images, then slight rotation and alignment errors were corrected
2. The image was interpolated to a higher pixel grid, which also deconvolves the response of the CCD sensor
3. The interpolated region was averaged column-wise and normalized to obtain an approximate aerial image



# SHARP Wavefront Extraction

- Pupil amplitude *and* phase variation was extracted
- 8 iterations were necessary to converge on a solution (18 hour runtime)
- Pupil *phase* RMS of  $61.3\text{m}\lambda$  or  $0.828\text{nm}$
- Pupil *amplitude* RMS of 10.18%

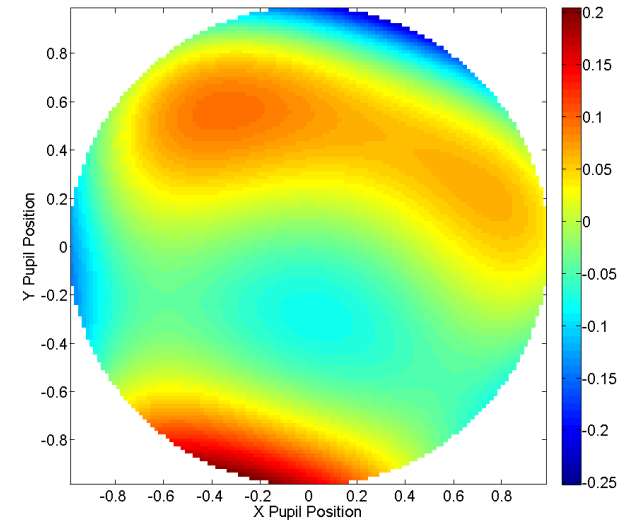


Aberration Name	Extracted Value [ $m\lambda$ ]
Astigmatism $90^\circ$	-18.32
Astigmatism $45^\circ$	-1.20
Coma X	-6.56
Coma Y	-118.55
Spherical	-39.65
Trefoil X	+67.97
Trefoil Y	+92.16

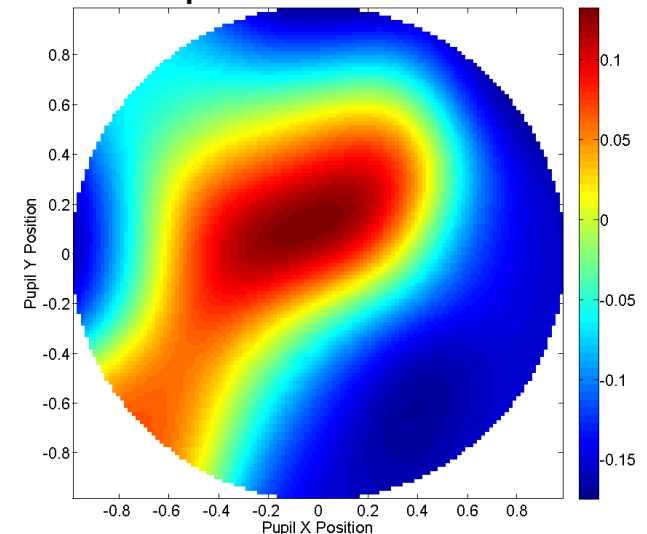
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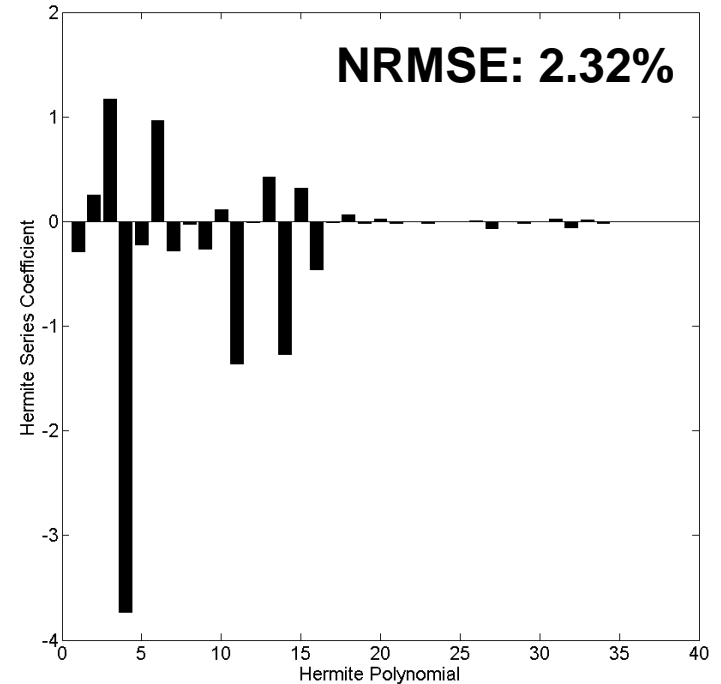
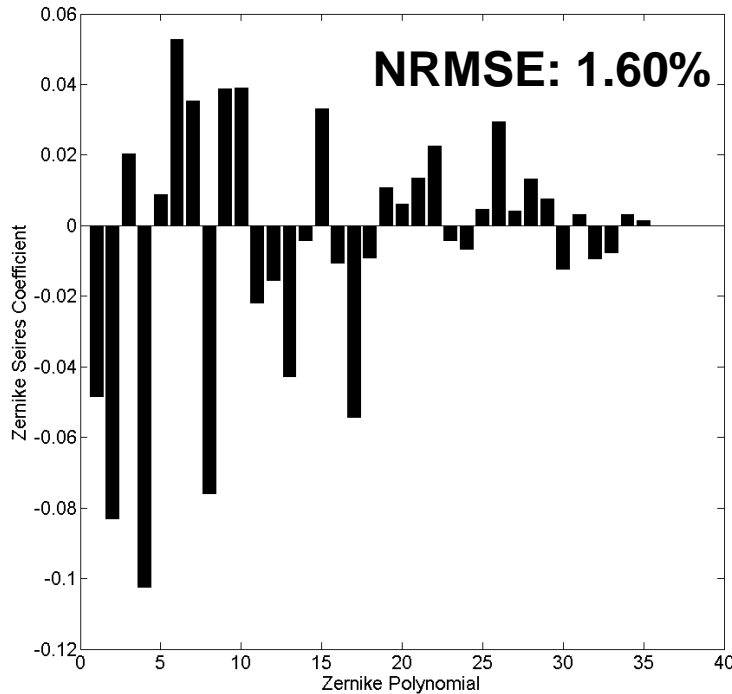
Phase Variation



Amplitude Variation



# SHARP Amplitude Expansions



- By visual inspection the amplitude appears to vary primarily around zero-frequency
- Amplitude function expanded in Zernike polynomials and Hermite polynomials
- Most Zernike polynomials are zero at the origin, so Hermite polynomials provide the better expansion

# Concluding Remarks

- Developing framework for pupil amplitude and phase extraction via image data
- Tested experimentally using NXE:3100 EUV scanner and SHARP EUV microscope
- Hermite polynomials appear to provide better fit to pupil amplitude variation than Zernike polynomials
- NXE:3300 exposures planned
- Future work will focus on studying pupil amplitude variation further and reducing runtime





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